



Attorneys Docket No.: 4935-28A/ETC I/METAL/JB1

Patent

2829

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Steven Verhaverbeke et al.  
U.S. Serial No: 09/945,454  
Filed: August 31, 2001  
For: A METHOD AND APPARATUS FOR  
PROCESSING A WAFER

Examiner: Kilday, Lisa A  
Art Unit: 2829

FIRST CLASS CERTIFICATE OF MAILING  
(37 c.f.r. § 1.8(a))

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Date

Commissioner of  
Patents and Trademarks  
Washington, D.C. 20231

RESPONSE TO ELECTION REQUIREMENT

Sir:

In response to the Election Requirement mailed August 28, 2002, applicant(s) hereby elects to prosecute Group I claims, claims 1-5, 11-25 and 44-51 drawn to a single wafer wet/dry cleaning apparatus. As such, applicant(s) elects to withdraw Group II-V claims, claims 6-10, 26-43 and 52-79 drawn to a non-elected method.

If there are any additional charges, please charge Deposit Account No. 02-2666.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN

Date: 9/27/02

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